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**PATENT APPLICATION**

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#2/Submission  
of  
Declaration

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takua NAKAMURA

Application No.: 10/080,712

Filed: February 25, 2002

Docket No.: 111856

For: METHOD FOR ASSESSING IRRADIATION INTENSITY OF A LASER BEAM, AN  
APPARATUS FOR ASSESSING IRRADIATION INTENSITY USED UNDER THIS  
METHOD, AND A LASER BEAM IRRADIATION SYSTEM

**SUBMISSION OF ORIGINAL DECLARATION**

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

Submitted herewith is the original signed Declaration of the Inventor. This  
Declaration corresponds to the facsimile copy of the Declaration filed on February 25, 2002.

Respectfully submitted,

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Date: March 15, 2002

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